

11

DECLARATION

I hereby state that the work described in this thesis entitled "A Study of the effect of Ion Implantation on electrical conduction and anelastic relaxation in some semiconducting, semimetallic and metallic systems" has not been submitted previously to this or any other University for the Ph.D. degree, or any other degree, diploma or academic award.

Regarding authors contribution to joint work

This work has been done under the guidance of Dr.V.N.Bhoraskar. The work on the fabrication of ion implantation machine was done jointly with Dr.S.B.Ogale.

Anjali S. Ogale

Mrs Ogale Anjali S.
Department of Physics
University of Poona

Certified by :

V.N. Bhoraskar
Dr. V.N. Bhoraskar
Reader in Physics,
Department of Physics
University of Poona

May 1982